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A New SOLT Calibration Method for Leaky On-wafer Measurements Using a 10-term Error Model

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Abstract—We present a new Short-Open-Load-Thru (SOLT) calibration method for on-wafer S -parameter measurements. The new calibration method is based on a 10-term error model which is a simplified version of the 16-term error model. Compared with the latter, the former ignores all signal leakages except the ones between the probes. Experimental results show that this is valid for modern vector network analyzers (VNA). The advantage of using this 10-term error model is that the exact values of all error terms can be obtained by using the same calibration standards as the conventional SOLT method. This avoids not only the singularity problem with approximate methods, such as least squares, but also the usage of additional calibration standards. In this paper, we first demonstrate how the 10-term error model is developed and then the experimental verification of the theory is given. Finally, a practical application of the error model using a 10 dB attenuator from 140 GHz to 220 GHz is presented. Compared with the conventional SOLT calibration method without crosstalk corrections, the new method shows approximately 1 dB improvement in the transmission coefficients of the attenuator at 220 GHz.

Index Terms—Calibration, Error model, Millimeter-wave measurements, On-wafer measurements, Scattering parameters.

I. INTRODUCTION

FOR TWO-PORT on-wafer measurements, the probe tips are often very close to each other, causing probe-to-probe signal leakages or crosstalk as illustrated in Fig. 1. The crosstalk between probes affects measurement accuracy if it is not considered properly during system calibration and actual measurements. Fig. 2 shows measured uncorrected raw data of $|S_{21}|$ for different impedance standards i.e., Open, Short and Load on a commercial calibration substrate with a fixed probe separation of 150 μm in the frequency range from 140 GHz-220 GHz. These results show not only the crosstalk exists and could be as high as -15 dB but also the crosstalk is dependent on frequency and the devices-under-test (DUTs). The crosstalk is considered to consist of two parts: one is from the fringing effect which is related to the separation between the two probes.

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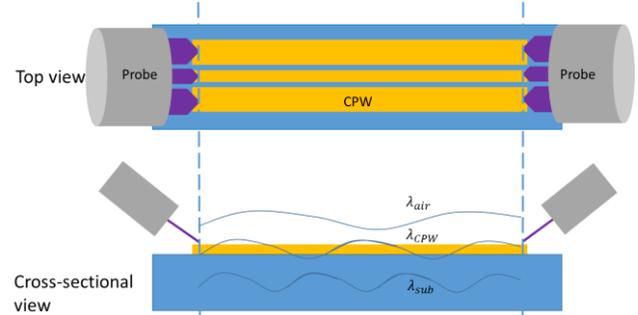


Fig. 1. Illustration of two-port on-wafer measurement and the probe-to-probe signal leakage due to fringing effects.

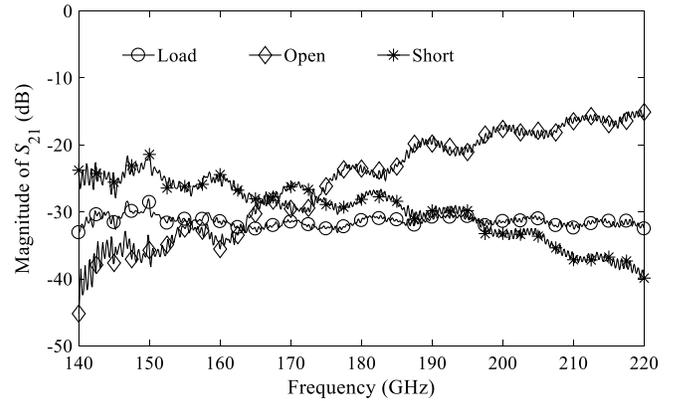


Fig. 2. Measured uncorrected raw data of $|S_{21}|$ for different impedance standards on a commercial calibration substrate with a fixed probe separation of 195 μm .

However, for on-wafer measurements at higher frequencies, e.g., 110 GHz and above, the probes need to be brought much closer together to reduce system losses, and thus the fringing effect of the probes makes the probe-to-probe coupling stronger. This type of crosstalk contributes to the systematic error and can be corrected using system calibration; the other is related to the impedance of the DUT and it is difficult to correct using

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currently available system error models.

Most calibration methods used for coaxial, waveguide or low-frequency on-wafer measurements, such as Short-Open-Load-Thru (SOLT), Thru-Reflect-Line (TRL) and Line-Reflect-Match (LRM), use either 8-term or 12-term error models that do not contain corrections for the crosstalk because it is either non-existent or negligibly small [1]-[4]. The 16-term error model introduced by Speciale in 1977 was the first to take into account the crosstalk between the VNA's measurement ports [5]. Later Butler *et al.* [6], and Heuermann and Schiek [7] demonstrated that the 16-term error model was able to correct crosstalk in a coaxial VNA system by deliberately adding an enclosed coaxial coupling network between the VNA and its test ports. It was Silvonen *et al.* [8], [9] who first implemented the 16-term error model for on-wafer measurements and developed the Line-Reflect-Reflect-Match (LRRM) calibration method. A simpler error model was then developed, based on the Short-Open-Load-Reciprocal (SOLR) method, as described in [10]. More recently, Williams *et al.* [11] investigated crosstalk and crosstalk corrections in a coplanar-waveguide (CPW) system using the 16-term error model and demonstrated that a number of factors, including the length of the access lines, transverse dimensions, separation between the crosstalk standards, and the substrate configuration etc. may play a role in correcting the crosstalk, and hence the achieved measurement accuracy.

There is no doubt that the probe-to-probe crosstalk should be corrected accurately during system calibration and/or measurement. However, the fundamental problem with the 16-term error model is that there exists one or more singular values that make the exact values for all error terms not solvable if only four sets of two-port calibration standards are used. Numerical simulations performed in [12] show that at least five sets of two-port calibration standards including one or more nonsymmetrical standard pair (e.g., load-short) are required to completely solve all the error terms in the 16-term error model. Using additional calibration standards is not desirable for on-wafer calibrations especially at millimeter-wave frequencies because it is difficult to design and fabricate the standards with sufficient accuracy.

In order not to use additional calibration standards, several methods have been developed to solve the error terms in the 16-term error model. One of the solutions is using the singular value decomposition (SVD) method to remove the singular values and obtain approximate values for the error terms [6], [13]. Other studies suggested that four or even three sets of two-port standards, as in the super-thru-short-delay (super-TSD) approach, are possible under certain circumstances [5], [14]. In [8], four sets of calibration standards were also used, but the method was only suitable for reciprocal systems, or two-tier on-wafer calibrations.

In this paper, we propose a new and more general calibration method using a 10-term error model. The model is a simplified version of the 16-term error model but ignores all leakages except the crosstalk between the test ports, or probes in this case. The main advantage of this model is that the singularity problem is avoided and all error terms in the model can be

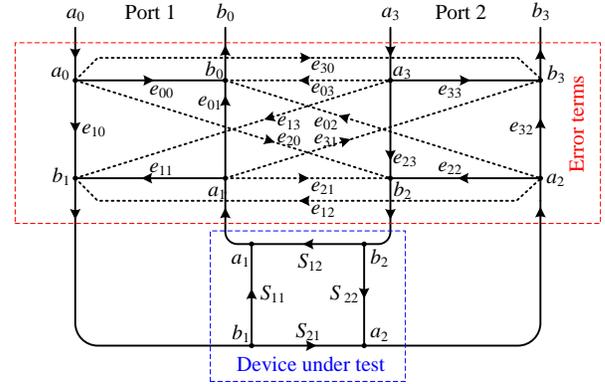


Fig. 3. Signal flow chart of the 16-term error model (Re-drawn from [6]). The solid lines represent the actual signal transmission and reflection paths; the dotted lines represent the leakages or crosstalk.

solved exactly without any assumptions or the need to introduce additional calibration standards. Only four sets of two-port standards that can be the same as the conventional SOLT standards, i.e., short-short, open-open, load-load and a thru are required. The outline of the paper is as follows. The theory about the 10-term error model is first developed. Then experimental verification of the leakages is given. Finally, we demonstrate the implementation of the new error model for measurements of a 10 dB attenuator and the results are compared with the conventional SOLT calibration as well as a numerical model.

II. THEORY

A. The 16-term Error Model

Fig. 3 shows the signal flow chart of the 16-term error model for a two-port on-wafer S -parameter measurement system [6]. The solid lines represent the actual signal transmission and reflection paths, whereas the dotted lines represent the leakages or crosstalk between nodes. Compared with the conventional 8-term error model, the 16-term error model uses the same error network as a four-port network but adds 8 signal leakage paths: between the test ports (in our case, these are the probe tips), e_{21} and e_{12} ; between the test ports and the receivers, e_{13} , e_{31} , e_{02} , e_{20} ; and, between the sources and the receivers inside the VNA, e_{30} and e_{03} . The error terms can be expressed in the form of a matrix [6] as shown in (1).

$$E = \begin{bmatrix} E_1 & E_2 \\ E_3 & E_4 \end{bmatrix} = \begin{bmatrix} e_{00} & e_{03} & e_{01} & e_{02} \\ e_{30} & e_{33} & e_{31} & e_{32} \\ e_{10} & e_{13} & e_{11} & e_{12} \\ e_{20} & e_{23} & e_{21} & e_{22} \end{bmatrix} \quad (1)$$

Using S_a to represent the actual S -parameters of the DUT or the calibration standards and S_m to represent the measured S -parameters of the DUT or the calibration standards, we have the following

$$S_m = E_1 + E_2 S_a (I - E_4 S_a)^{-1} E_3 \quad (2)$$

$$S_a = \{E_3 (S_m - E_1)^{-1} E_2 + E_4\}^{-1} \quad (3)$$

where I is the identity matrix. S_m and S_a can also be represented as

$$S_m = \begin{bmatrix} b_0/a_0 & b_0/a_3 \\ b_3/a_0 & b_3/a_3 \end{bmatrix} \quad (4)$$

$$S_a = \begin{bmatrix} a_1/b_1 & a_1/b_2 \\ a_2/b_1 & a_2/b_2 \end{bmatrix} \quad (5)$$

Since the error terms in (3) are nonlinear and difficult to solve, one solution is to convert (1) to cascading T -parameters, as shown below in (6), and then (2), (3) can be rewritten as (7), (8), respectively.

$$T = \begin{bmatrix} T_1 & T_2 \\ T_3 & T_4 \end{bmatrix} = \begin{bmatrix} t_0 & t_1 & t_4 & t_5 \\ t_2 & t_3 & t_6 & t_7 \\ t_8 & t_9 & t_{12} & t_{13} \\ t_{10} & t_{11} & t_{14} & t_{15} \end{bmatrix} \quad (6)$$

$$S_a T_1 + T_2 - S_m T_3 S_a - S_m T_4 = 0 \quad (7)$$

$$S_a = (T_1 - S_m T_3)^{-1} (S_m T_4 - T_2) \quad (8)$$

At first glance, it appears that the four T terms in (7) can be solved using four equations formed with four sets of known calibration standards. Once the T terms are solved the actual S -parameters of a DUT can be derived using (8). However, this is not the case, because there are singularities in (2), and therefore (7), which make equations (7) and (8) not solvable with only four sets of equations. It has been demonstrated that at least five two-port calibration standards, including one nonsymmetrical pair (e.g., load-short), can solve the equations accurately [12]. Alternatively, an approximation method, such as the SVD method, can be used to get close to (but not equal to) the exact values of the error terms [6], [13].

B. Error Term Matrix Transformation

It is necessary to include the matrix transformation between the E matrix and the T matrix before introducing the 10-term error model [14].

$$E = \begin{bmatrix} T_2 T_4^{-1} & T_1 - T_2 T_4^{-1} T_3 \\ T_4^{-1} & -T_4^{-1} T_3 \end{bmatrix} = \frac{1}{\Delta} \begin{bmatrix} \Delta_1 & \Delta_2 & \Delta t_0 - \Delta_1 t_8 - \Delta_2 t_{10} & \Delta t_1 - \Delta_1 t_9 - \Delta_2 t_{11} \\ \Delta_3 & \Delta_4 & \Delta t_2 - \Delta_3 t_8 - \Delta_4 t_{10} & \Delta t_3 - \Delta_3 t_9 - \Delta_4 t_{11} \\ t_{15} & -t_{13} & t_{10} t_{13} - t_8 t_{15} & t_{13} t_{11} - t_9 t_{15} \\ -t_{14} & t_{12} & t_8 t_{14} - t_{10} t_{12} & t_9 t_{14} - t_{11} t_{12} \end{bmatrix} \quad (9)$$

$$T = \begin{bmatrix} E_2 - E_1 E_3^{-1} E_4 & E_1 E_3^{-1} \\ -E_3^{-1} E_4 & E_3^{-1} \end{bmatrix} = \frac{1}{x} \begin{bmatrix} x e_{01} + x_1 e_{00} + x_2 e_{03} & x e_{02} + x_3 e_{00} + x_4 e_{03} & \dots \\ x e_{31} + x_1 e_{30} + x_2 e_{33} & x e_{32} + x_1 e_{30} + x_2 e_{33} & \dots \\ x_1 & x_3 & \dots \\ x_2 & x_4 & \dots \\ \dots & e_{00} e_{23} - e_{03} e_{20} & e_{03} e_{10} - e_{00} e_{13} \\ \dots & e_{30} e_{23} - e_{33} e_{20} & e_{33} e_{10} - e_{30} e_{13} \\ \dots & e_{23} & -e_{13} \\ \dots & -e_{20} & e_{10} \end{bmatrix} \quad (10)$$

where

$$\Delta = t_{12} t_{15} - t_{13} t_{14} \quad (11)$$

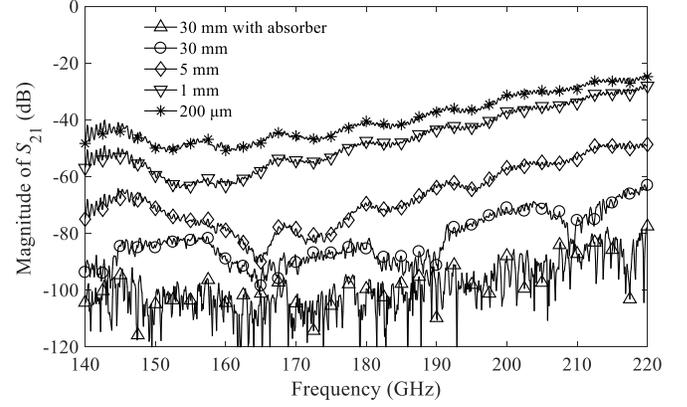


Fig. 4. Measured uncorrected raw data of $|S_{21}|$ for different separations between probes while probe tips are left in open air.

$$\Delta_1 = t_4 t_{15} - t_5 t_{14} \quad (12)$$

$$\Delta_2 = t_5 t_{12} - t_4 t_{13} \quad (13)$$

$$\Delta_3 = t_6 t_{15} - t_7 t_{14} \quad (14)$$

$$\Delta_4 = t_7 t_{12} - t_6 t_{13} \quad (15)$$

and

$$x = e_{10} e_{23} - e_{13} e_{20} \quad (16)$$

$$x_1 = e_{13} e_{21} - e_{23} e_{11} \quad (17)$$

$$x_2 = e_{20} e_{11} - e_{10} e_{21} \quad (18)$$

$$x_3 = e_{13} e_{22} - e_{23} e_{12} \quad (19)$$

$$x_4 = e_{20} e_{12} - e_{10} e_{22} \quad (20)$$

As long as the T error terms are calculated, the E error terms can be derived using (9) and (11)-(15). On the contrary, the T error terms can be obtained from (10) and (16)-(20).

C. The 10-term Error Model

Assuming all the leakage or crosstalk terms from Fig. 3 are zero, the 16-term error model reduces to the conventional 8-term error model that is widely applied in Thru-Reflect-Line (TRL), Line-Reflect-Match (LRM), and transmission type circuit-any circuit-unknown circuit (TCX) [15], [16] calibration methods. However, for on-wafer measurement the crosstalk error terms between probes, e_{21} and e_{12} , are necessary because the tips of both probes are exposed to the open environment and can be close to each other. The fringing effect from one probe couples energy to the other probe when they are within a close proximity. This is the case for components and transistors in monolithic millimeter-wave integrated circuits (MMICs). Fig. 4 shows the measured coupling between two G-band (from 140 GHz to 220 GHz) probes when they are placed in air and separated by various distances. The measured uncorrected raw data (i.e., the transmission coefficient S_{21}) is close to -20 dB at 220 GHz when the probes are separated by only 200 μm . The coupling will be higher when the probes are even closer and/or the frequency is higher. Therefore, it is necessary to remove, or calibrate out, the probe-to-probe crosstalk.

As shown in Fig. 3, error terms e_{30} and e_{03} are the leakage paths between the source and the receiver inside the VNA. For a modern network analyzer, the internal leakages are usually less than -60 dB (even at terahertz frequencies [17]) and so can

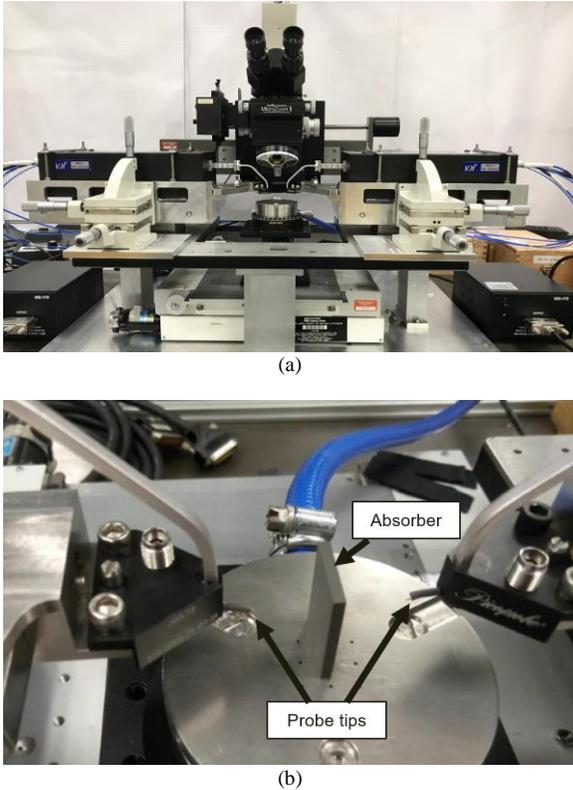


Fig. 5. (a) Photograph of the G-band (from 140 GHz to 220 GHz) on-wafer S -parameter measurement setup. (b) A close-up showing a microwave absorber placed between the two lifted probes used to obtain some of the data shown in Fig. 4.

TABLE I
SYSTEM CONFIGURATION

System Configuration	Model & Manufacturer / Parameters
VNA	PNA-X N5247A, Keysight
Frequency Extenders	WR5.1, VDI
Probe station	Customized Cascade (manual)
Probes	220-GSG-75-BT-M, GGB
No. of frequency points	801
IF bandwidth	100 Hz

be neglected. Other leakage terms, i.e., e_{20} , e_{02} , e_{31} and e_{13} , have no direct physical paths between nodes but are the leakages from the VNA's ports to the reference planes, which are low-level noise and so can also be neglected [18]. Our experimental results also demonstrate the leakages from these terms are minimal. We will illustrate this point later.

In summary, based on the aforementioned analysis we consider omitting all leakage terms except e_{21} and e_{12} in the 16-term error model. Thus we have

$$e_{20} = e_{02} = e_{31} = e_{13} = e_{30} = e_{03} = 0 \quad (21)$$

so that only 10 error terms remain non-zero in the 16-term error model which now becomes a 10-term error model.

By substituting (21) into (10), the T matrix becomes

$$T = \begin{bmatrix} e_{01} - e_{00}e_{11}/e_{10} & -e_{00}e_{12}/e_{10} & e_{00}/e_{10} & 0 \\ -e_{21}e_{33}/e_{23} & e_{32} - e_{22}e_{33}/e_{23} & 0 & e_{33}/e_{23} \\ -e_{11}/e_{10} & -e_{12}/e_{10} & 1/e_{10} & 0 \\ -e_{21}/e_{23} & -e_{22}/e_{23} & 0 & 1/e_{23} \end{bmatrix} \quad (22)$$

Thus, the 16 unknowns in (10) are reduced to 12 unknowns in

(22). In the meantime, we can also obtain the following equations

$$t_1 t_{12} = t_4 t_9 \quad (23)$$

$$t_2 t_{15} = t_7 t_{10} \quad (24)$$

Although these two equations, i.e., (23) and (24) are not used for solving the error model, they provide useful supplementary information. For example, this information can be used to verify whether the solution to the error model is within the allowed range.

Now if we use four sets of known two-port standards to perform the calibration, we will have a total of 18 equations, which are the 16 equations from (7) and the two equations from (23), (24), to solve for the 12 unknowns. However, experiments have shown that sufficient accuracy is achieved by using only the 16 (linear) equations from (22) to solve for the 12 unknowns. If the additional two (nonlinear) equations in (23), (24) are included, the accuracy of the solutions is not improved. In fact, the accuracy can be made worse by the need to use a more complicated nonlinear constrained optimization algorithm to solve for these additional terms.

To solve the overdetermined 12 unknowns for the T matrix, the homogeneous equations can be transformed to nonhomogeneous equations by normalizing the 12 unknown terms to any one term whose value is not zero. It is preferable to do this with t_{12} or t_{15} . Once this is done, the remaining 11 terms are calculated as a function of the normalized term. The detailed calculation can be found in textbooks (or refer to [6], [14]) and so will not be repeated here. However, we carried out a simulation test on singularities using our in-house developed MATLAB code and so we were able to confirm that there is no singular solution for the E error terms.

III. IMPLEMENTATION AND RESULTS

A. Verification of Leakages

In the previous section, we described how the 10-term error model was derived from the 16-term error model by assuming that all leakage terms, apart from the probe-to-probe crosstalk, were neglected, without providing any evidence for the validity of this assumption. We now show experimentally that the assumption is valid. Because all leakage terms, except e_{21} and e_{12} , are independent from the separation between the two probes, we can therefore measure the leakages when the two probes are completely isolated; in other words, when e_{21} and e_{12} are equal to zero.

Fig. 5a shows the G-band (from 140 GHz to 220 GHz) on-wafer S -parameter measurement setup, including a manual probe station, at the UK National Physical Laboratory (NPL). Two probes from GGB Industries, Inc, are used in the setup. The system configuration is shown in Table I. During the leakage verification measurement, the two probes were lifted up in the air above the chuck by approximately 20 mm. Uncorrected raw transmission coefficients S_{21} were measured as the separation between the two probes was increased. The measurement results, plotted in Fig. 4, show that the transmission coefficients decrease as the separation distance between the probes increases, and reach -80 dB when the two

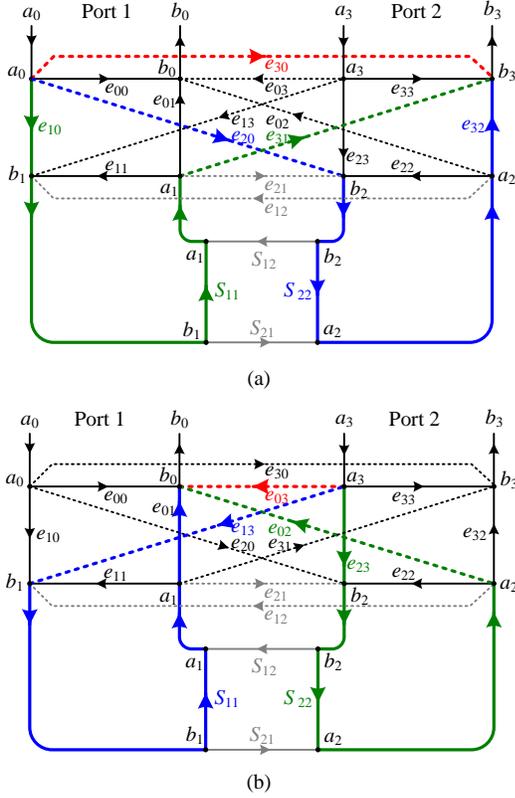


Fig. 6. (a) Forward signal flow chart of a two-port on-wafer network when two probes are “completely” isolated. (b) Reverse signal flow chart of a two-port on-wafer network when two probes are “completely” isolated.

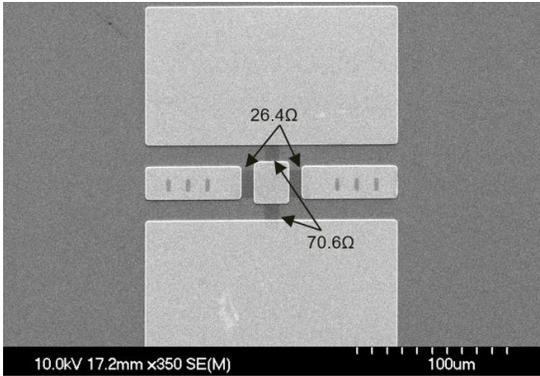


Fig. 7. SEM image of the attenuator. The attenuator was fabricated on a 4-inch semi-insulating GaAs substrate using a standard photolithography method.

probes are separated by 30 mm and -100 dB when a microwave absorber (Cascade PN 116-344) is inserted between the probes, as shown in Fig. 5b. In this case, the two probes are completely isolated and there is no probe-to-probe coupling. In this situation, the transmission coefficients represent all signal leakages apart from e_{21} and e_{12} . If we now re-draw the signal flow chart shown in Fig. 3 by separating the forward and the reverse paths, we mimic how a VNA measures the S -parameters of a two-port network. This is shown in Fig. 6. Taking the forward transmission path as an example, one can notice that the signal received at b_3 consists of three paths which are

1. e_{30} , a direct path from a_0 to b_3 , marked in red;
2. $e_{20} - S_{22} - e_{32}$, marked in blue;
3. $e_{10} - S_{11} - e_{31}$, marked in green.

As the transmission coefficients are below -80 dB, we can conclude that each individual path is also below -80 dB which is considered to be negligible. This simple experiment proves that our previous assumption of zero signal leakages, apart from e_{21} and e_{12} , is valid. In the next section, we demonstrate the implementation of the 10-term error model with the conventional SOLT standards for a G-band on-wafer system.

B. Implementation of the Error Model

A series of two-port standards including open-open pairs, short-short pairs, load-load pairs, and thru were fabricated on a semi-insulating GaAs substrate using a standard photolithography technology. A 400 nm layer of gold was deposited for the conductors and a thin layer of nickel-chrome alloy was used for the resistors. The substrate was then thinned down to 100 μm after all circuits were made. To evaluate the calibration method, a 10 dB attenuator was designed with the aid of numerical software – *Computer Simulation Technology (CST) Microwave Studio* – and fabricated on the same substrate. The simulation uses wave ports, and are designed to determine the actual attenuator’s response to a pure CPW mode that we hope to measure. Fig. 7 shows a scanning electron microscope (SEM) image of the attenuator. All aforementioned components have the same edge-to-edge distance (i.e., 160 μm) in order to keep the crosstalk constant during calibration and measurement. We defined the offset of the standards with reference to [19]. We used the setup shown in Fig.5a to obtain uncorrected raw data for the SOLT calibration standards and the attenuator and then post-processed the data by implementing the conventional 12-term error model (assuming no probe-to-probe crosstalk) and the proposed 10-term error model.

Fig. 8 shows comparisons of the transmission coefficients of the attenuator, corrected using the two error models, with the simulated data (using CST). In addition, we also plot the results corrected using the conventional SOLT method using standards on GGB’s CS-15 calibration wafer (i.e., the off-wafer results). We also compared the results with other commonly used on-wafer calibration methods, i.e., the Short-Open-Load-Reciprocal (SOLR) method, and the 16-term correction using SVD method [6], [13], with only four standards (i.e., a short-short pair, an open-open pair, a load-load pair and a thru standard) from the GaAs substrate. It is clear that the magnitude corrected by 16-term correction and our method are significantly closer to the simulation results, compared to either the “on-wafer” 12-term SOLT method, the “off-wafer” 12-term SOLT method, or the SOLR method. The main reason for this is that these calibration techniques do not correct for the effect of crosstalk properly; therefore the crosstalk contributes to the total power transmission between the probes. Besides, from Fig.8 we can also see that there are less ripples in the trace using 10-term SOLT correction compared with that using 16-term correction. The main reason for this is that there is not enough information for the 16-term error model even though the SVD algorithm is applied for eliminating singular solutions. The 10-term error, reported in this paper, can effectively avoid singular solutions, as well as using only four standards.

In addition, for the “off-wafer calibration”, the probe launch

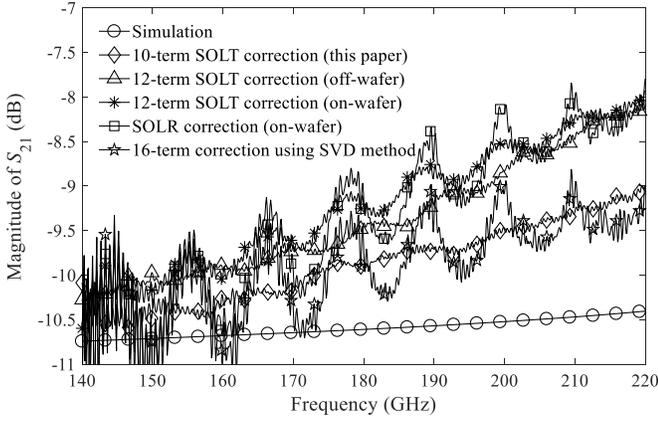


Fig. 8. Comparison of attenuator transmission coefficients measured with and without crosstalk corrections.

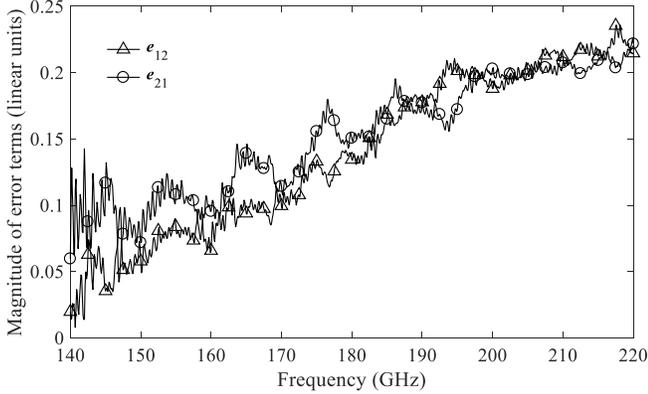


Fig. 9. Magnitude of e_{12} and e_{21} terms. To some extent, these error terms represent crosstalk between probes.

difference between the calibration substrate and the DUT also makes a difference because pad parasitic effects will cause additional measurement error. On the other hand, for the “on-wafer calibration”, the standards are fabricated on the same wafer as the DUT. The standards are created with the identical launch as the DUT, with the same metal pad pattern and substrate dielectric.

Fig. 9 shows the derived probe-to-probe crosstalk, in linear units, using the 10-term error model. The two error terms e_{21} and e_{12} represent the forward and reverse leakage paths between the probes. One can see that the crosstalk term increases as a function of frequency and reaches 0.2 at around 200 GHz. This amount of error could cause a significant effect on a device measurement of gain or insertion loss, if not properly corrected.

IV. CONCLUSION

We have presented a new SOLT calibration method using a 10-term error model which is different from the conventional SOLT method in which a 12-term error model is used. The proposed 10-term error model is a simplified version of the 16-term error model that only takes into account the probe-to-probe crosstalk. Experimental results have shown this assumption to be acceptable. With this assumption, the number of error terms in the 16-term error model is reduced and therefore a complete solution without singularities can be derived using four sets of two-port standards. The implementation of the calibration

method was carried out on a G-band on-wafer system and tested using a 10 dB attenuator. The results show that the new calibration method is much better than the conventional SOLT method by achieving an almost 1 dB (i.e., 10 %) improvement in measurement accuracy. In addition, one can also see that the magnitude of the crosstalk coefficients, or error terms, increases as the frequency increases and can play a significant role in the actual device measurement.

This paper has only discussed the correction of probe coupling when the crosstalk is assumed constant. In fact, the probe coupling may also contain some multi-modal signals which are more difficult to characterize. However, the experimental results in this paper have shown that the crosstalk correction technique described in this paper has produced substantial improvement to on-wafer S-parameter measurements. In the future, we intend to extend this work to take account of any effects that may be present due to multi-mode probe coupling.

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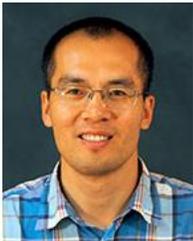
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